

Title (en)  
METHOD OF FORMING LOW-DIELECTRIC-CONSTANT AMORPHOUS SILICA COATING AND LOW-DIELECTRIC-CONSTANT AMORPHOUS SILICA COATING OBTAINED BY THE METHOD

Title (de)  
VERFAHREN ZUR HERSTELLUNG EINER BESCHICHTUNG AUS AMORPHEM SILIZIUMOXID MIT NIEDRIGER DIELEKTRIZITATSKONSTANTE UND DURCH DIESES VERFAHREN ERHALTENE BESCHICHTUNG AUS AMORPHEM SILIZIUMOXID MIT NIEDRIGER DIELEKTRIZITATSKONSTANTE

Title (fr)  
PROCEDE DE FABRICATION D'UN REVETEMENT DE SILICE AMORPHE A FAIBLE CONSTANCE DIELECTRIQUE ET REVETEMENT AINSI OBTENU

Publication  
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Application  
**EP 03758926 A 20031027**

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Abstract (en)  
[origin: EP1564798A1] The present invention relates to an amorphous silica-based coating film with a low specific dielectric constant of 2.5 or below and the Young' s modulus of 6.0 GPa or more and having excellent hydrophobic property, and to a method of forming the same. A liquid composition containing a silicon compound obtained by hydrolyzing tetraalkyl ortho silicate (TAOS) and specific alkoxysilane (AS) in the presence of tetraalkyl ammonium hydroxide (TAAOH) is prepared. The liquid composition is then applied on a substrate, heated and cured to obtain a coating film. The coating film obtained as described has a smooth surface and also has specific micropores therein. <IMAGE>

IPC 8 full level  
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